

# Plasma Electrolytic Polishing

Technology Progress Development for Nb and Cu Substrate Preparation

## PEP Highlights



### What are the key benefits PEP?

- "Green"** water-based salt solutions! No HF acid!  
*Nb - NH<sub>4</sub>F & NaF, Cu - SUBUS or (NH<sub>4</sub>)<sub>2</sub>HPO<sub>4</sub> or K<sub>2</sub>P<sub>2</sub>O<sub>7</sub>*
- 5-30 times faster** than regular EP  
*Up to 30 μm/min, significant reduction polishing time from days to tens of minutes*
- Lowest roughness** 5-50 nm achievable  
*Efficient polishing! Equal thickness removal yield lowest roughness among competitors (EP, BCP, SUBU)*
- No preparation** of surface is required  
*PEP can substitute mechanical polishing steps (CBP, grinding, tumbling)*

### What are the limitations?

- High voltage & high current** input
- Rounding** of the edges
- High volume solution / surface area** ratio
- Cathode/Anode surface area** ratio  $\geq 1 - 10$
- Complex geometries:** caves, holes

### LNL Patents:

1x Nb 3x Cu

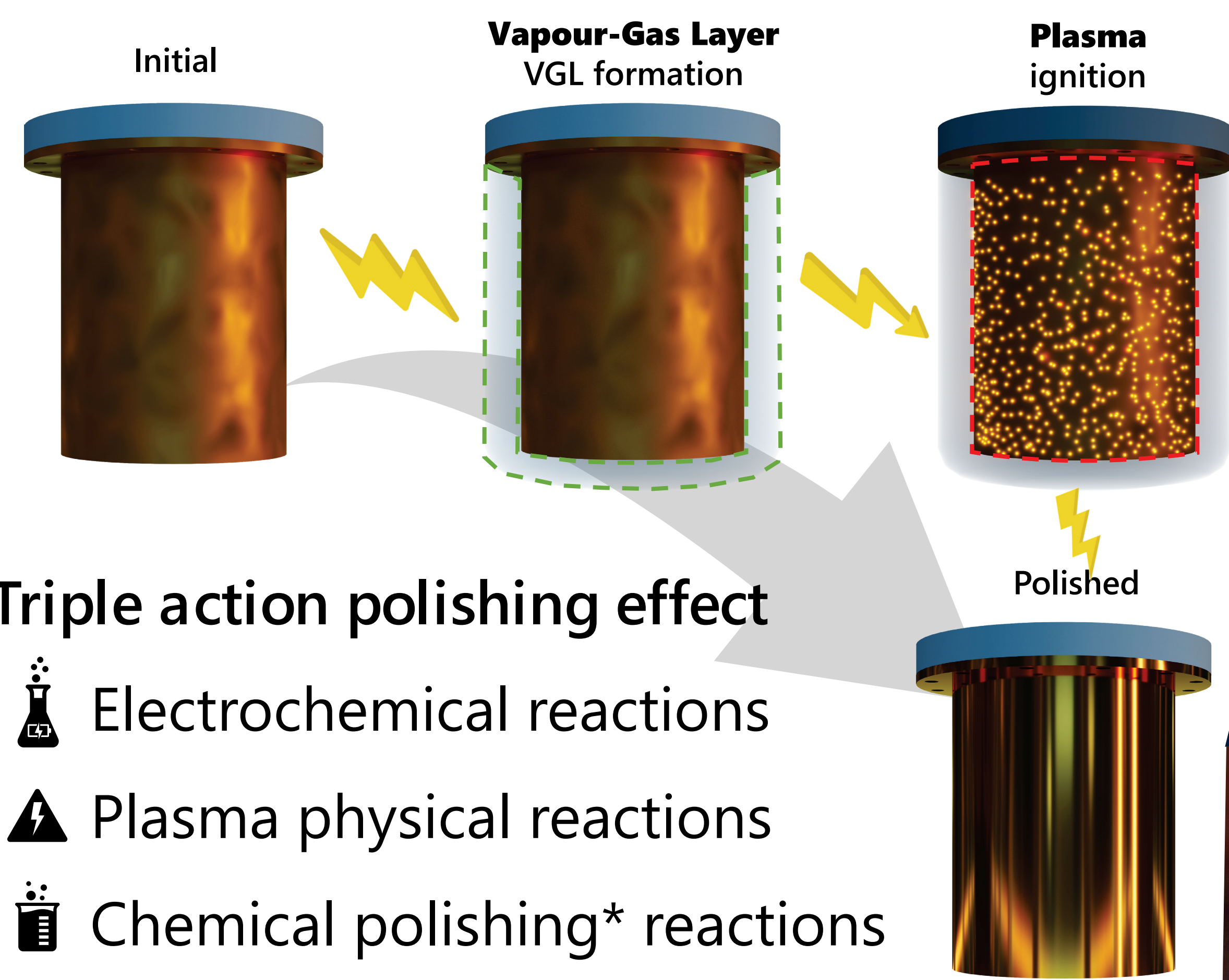
E. Chyhyrynets, O. Azzolini, R. Caforio, D. Fonnesu, D. Ford, G. Keppel, C. Pira, G. Marconato, A. Salmaso, F. Stivanello

## PEP scalability LNL plan

Patented Nb and Cu 4 origin compositions



## PEP Mechanism



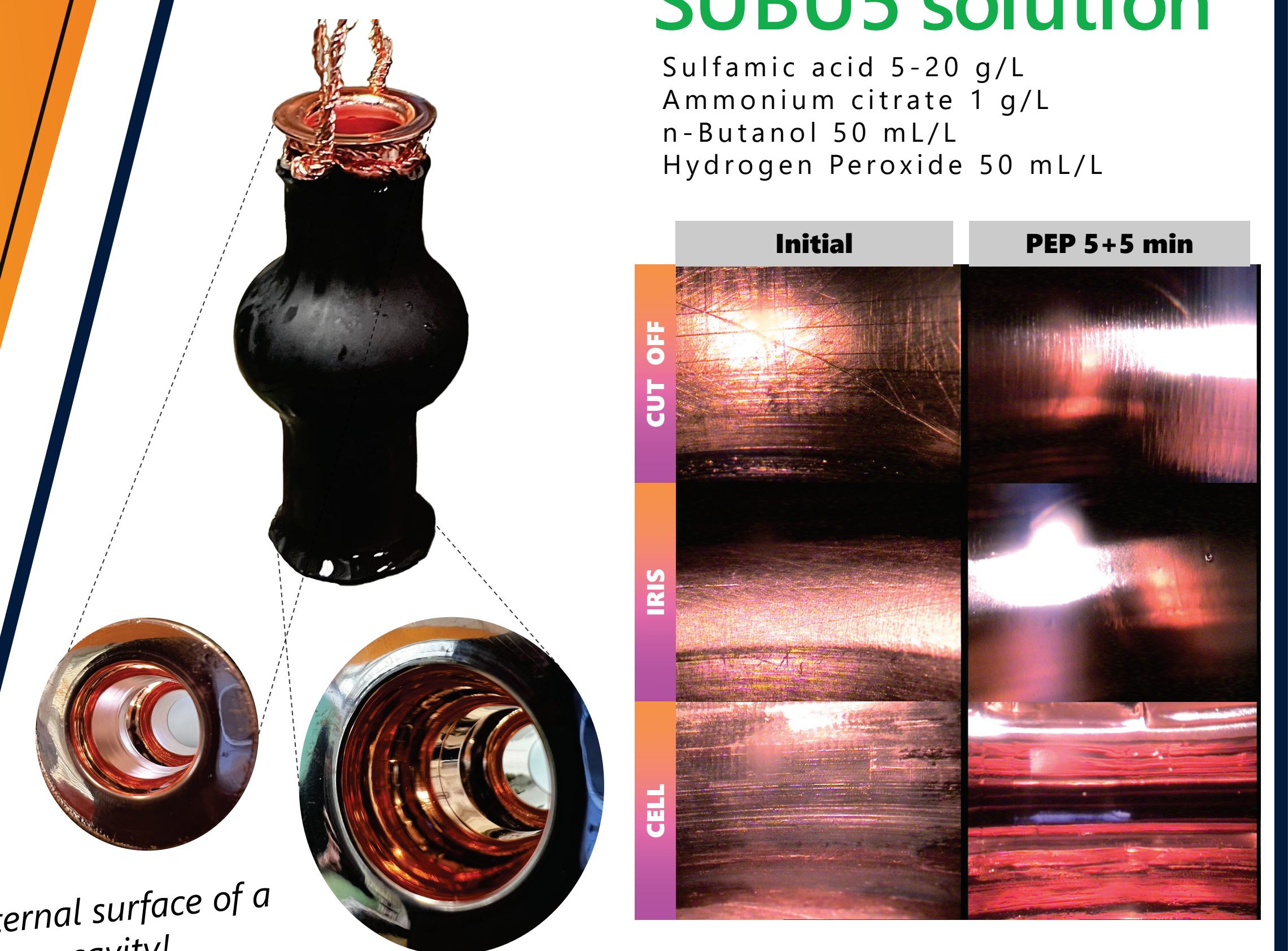
## 6 GHz cavity PEP internal polishing

No internal cathode was used!

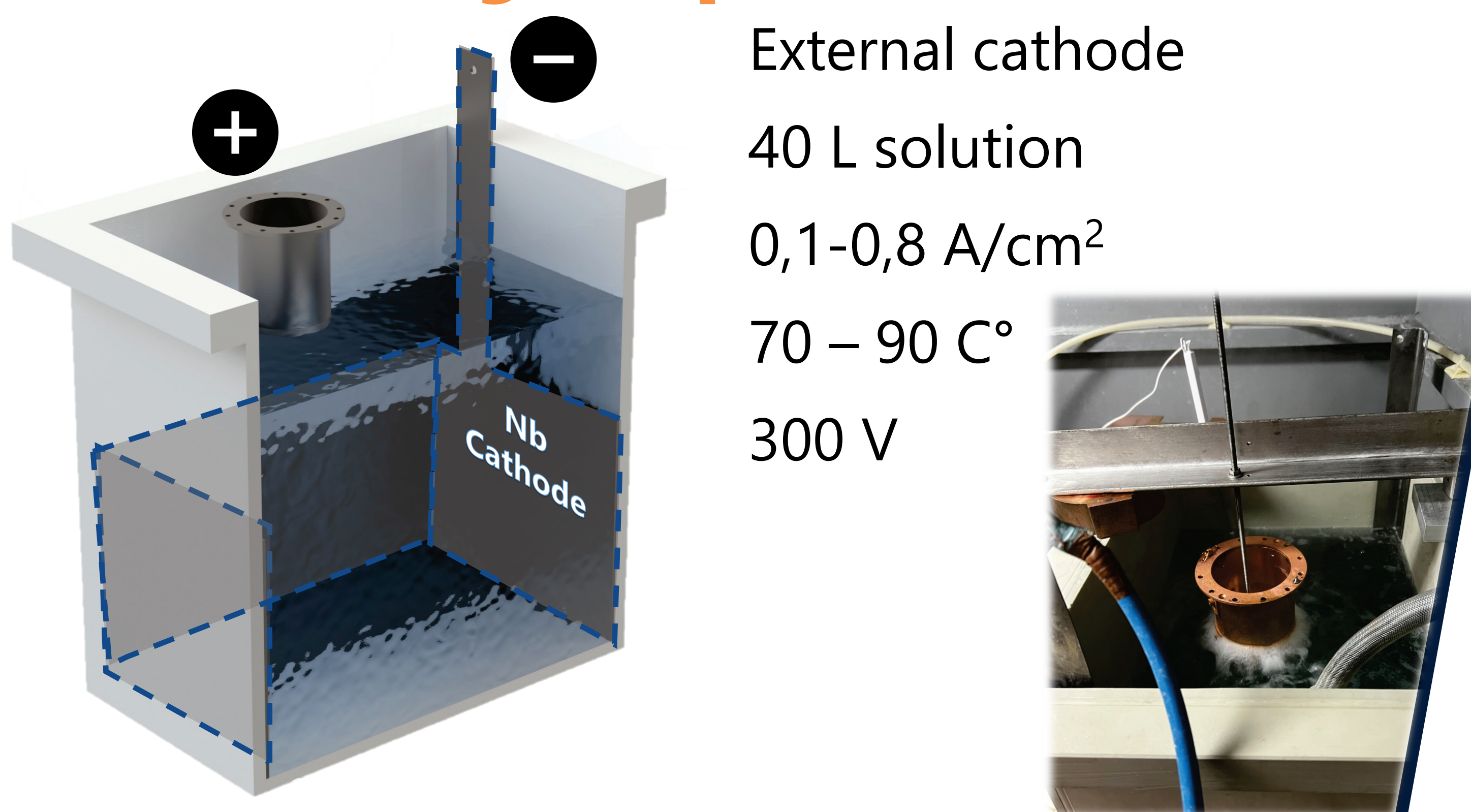
70 μm 30 A

### SUBU5 solution

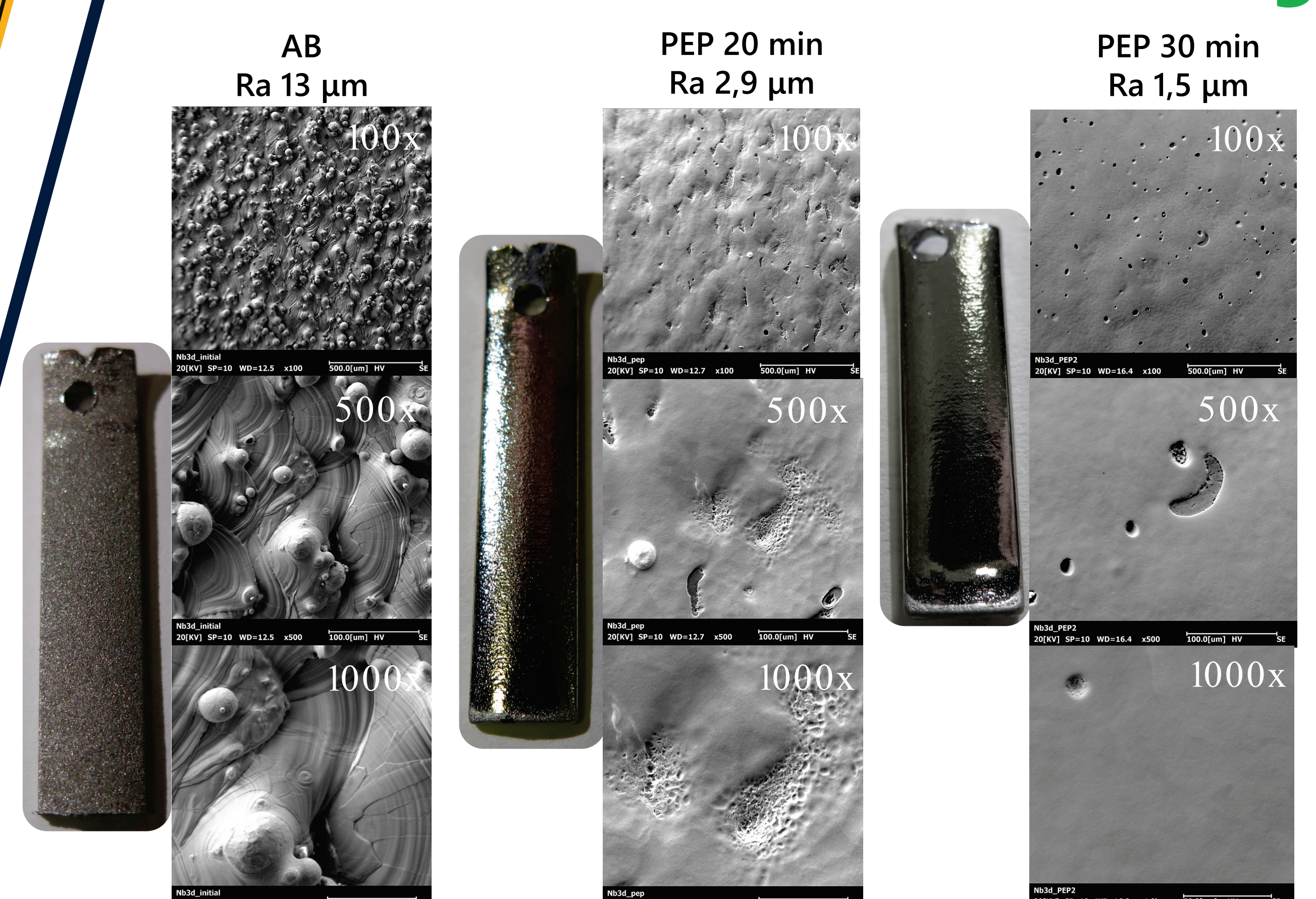
Sulfamic acid 5-20 g/L  
Ammonium citrate 1 g/L  
n-Butanol 50 mL/L  
Hydrogen Peroxide 50 mL/L



## LNL Polishing setup



## Nb Additive Manufacturing



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